



THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re the Application of: **Miwa KOZAWA et al.**

Group Art Unit: **1756**

Application Number: **10/670,291**

Examiner: **Daborah Chacko-Davis**

Filed: **September 26, 2003**

Confirmation Number: **6427**

For: **RESIST PATTERN THICKENING MATERIAL, PROCESS FOR
FORMING RESIST PATTERN, AND PROCESS FOR
MANUFACTURING SEMICONDUCTOR DEVICE**

Attorney Docket Number: **031181**

Customer Number: **38834**

PETITION FOR EXTENSION OF TIME

Commissioner for Patents
P. O. Box 1450
Alexandria, VA 22313-1450

August 21, 2007

Sir:

Applicants petition the Commissioner for Patents to extend the time for response to the Office Action dated March 21, 2007 for two months from June 21, 2007 to August 21, 2007.

Attached please find a check in the amount of \$450.00 for the cost of the extension. If any additional fees are due in connection with this paper, please charge Deposit Account No. 50-2866.

Respectfully submitted,

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